

Anthony G Fowler

List of Publications by Year in descending order

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20
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20
times ranked

318
citing authors

#	ARTICLE	IF	CITATIONS
1	MEMS for Nanopositioning: Design and Applications. Journal of Microelectromechanical Systems, 2017, 26, 469-500.	2.5	34
2	On-Chip Dynamic Mode Atomic Force Microscopy: A Silicon-on-Insulator MEMS Approach. Journal of Microelectromechanical Systems, 2017, 26, 215-225.	2.5	33
3	Internal Model Control for Spiral Trajectory Tracking With MEMS AFM Scanners. IEEE Transactions on Control Systems Technology, 2016, 24, 1717-1728.	5.2	30
4	Control of a Novel 2-DoF MEMS Nanopositioner With Electrothermal Actuation and Sensing. IEEE Transactions on Control Systems Technology, 2014, 22, 1486-1497.	5.2	27
5	High-stroke silicon-on-insulator MEMS nanopositioner: Control design for non-raster scan atomic force microscopy. Review of Scientific Instruments, 2015, 86, 023705.	1.3	27
6	An Omnidirectional MEMS Ultrasonic Energy Harvester for Implanted Devices. Journal of Microelectromechanical Systems, 2014, 23, 1454-1462.	2.5	25
7	On-Chip Feedthrough Cancellation Methods for Microfabricated AFM Cantilevers With Integrated Piezoelectric Transducers. Journal of Microelectromechanical Systems, 2017, 26, 1287-1297.	2.5	25
8	Q Control of an Active AFM Cantilever With Differential Sensing Configuration. IEEE Transactions on Control Systems Technology, 2019, 27, 2271-2278.	5.2	23
9	Design and Analysis of Nonuniformly Shaped Heaters for Improved MEMS-Based Electrothermal Displacement Sensing. Journal of Microelectromechanical Systems, 2013, 22, 687-694.	2.5	22
10	A 3-DoF MEMS ultrasonic energy harvester. , 2012, , .		10
11	MEMS Nanopositioner for On-Chip Atomic Force Microscopy: A Serial Kinematic Design. Journal of Microelectromechanical Systems, 2015, 24, 1730-1740.	2.5	8
12	Design and Characterization of a 2-DOF MEMS Ultrasonic Energy Harvester With Triangular Electrostatic Electrodes. IEEE Electron Device Letters, 2013, 34, 1421-1423.	3.9	6
13	Note: A silicon-on-insulator microelectromechanical systems probe scanner for on-chip atomic force microscopy. Review of Scientific Instruments, 2015, 86, 046107.	1.3	6
14	Q control of a microfabricated piezoelectric cantilever with on-chip feedthrough cancellation. , 2017, , .		4
15	A 4-DOF MEMS Energy Harvester Using Ultrasonic Excitation. IEEE Sensors Journal, 2016, 16, 7774-7783.	4.7	3
16	Characterization of a 2-DoF MEMS nanopositioner with integrated electrothermal actuation and sensing. , 2012, , .		2
17	4-DOF SOI-MEMS ultrasonic energy harvester. , 2015, , .		2
18	Nonlinear analysis of electrothermal position sensors with contoured heaters. , 2013, , .		1

#	ARTICLE	IF	CITATIONS
19	Tracking of spiral trajectories beyond scanner resonance frequency by a MEMS nanopositioner. , 2015, , .		1
20	A MEMS electromagnetic energy harvester using ultrasonic excitation. , 2013, , .		0